

Electronic Patent Application Fee Transmittal

Application Number:	10586788
Filing Date:	
Title of Invention:	Plasma excited chemical vapor deposition method, silicon/oxygen/nitrogen-containing-material and layered assembly
First Named Inventor/Applicant Name:	Zvonimir Gabric
Filer:	Ira Stuart Matsil/Nancy Milinkovich
Attorney Docket Number:	INF 2006 VJ 33543 US

Filed as Large Entity

U.S. National Stage under 35 USC 371 Filing Fees

Description	Fee Code	Quantity	Amount	Sub-Total in USD(\$)
Basic Filing:				
Pages:				
Claims:				
Miscellaneous-Filing:				
Oath/decl > 30 months from priority date	1617	1	130	130
Eng. Transl. > 30 mo. from priority date	1618	1	130	130
Petition:				
Patent-Appeals-and-Interference:				
Post-Allowance-and-Post-Issuance:				

Description	Fee Code	Quantity	Amount	Sub-Total in USD(\$)
Extension-of-Time:				
Miscellaneous:				
Total in USD (\$)				260